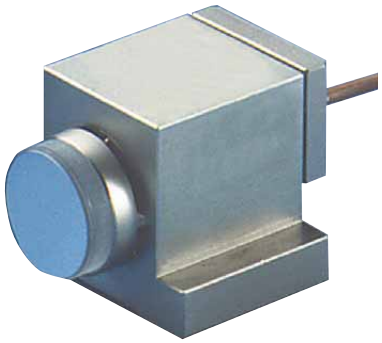
Piezo Steering Mirrors & Phase Shifters

For Photonics, Aerospace, Telecommunication, Medical

FAST



PRECISE

INDIVIDUAL

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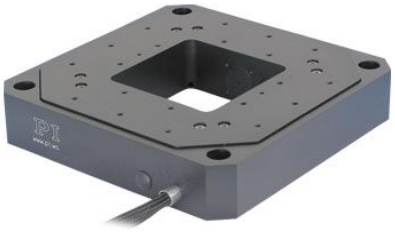
Piezo Tip/Tilt-Mirrors: Nanopositioning Platforms

The S-323 Z/tip/tilt platform integrates capacitive feedback sensors for highest resolution and stability

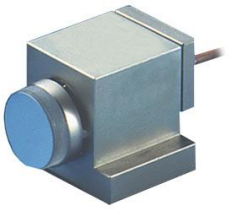
S-310.10 & S-316.10 phase shifter / tripod optics scanner & alignment systems

S-340 tip/tilt platform for mirrors up to 4" diameter

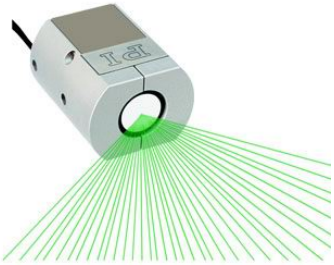
S-303 closed-loop and open loop high resolution phase shifters



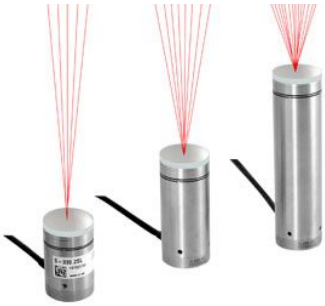
P-528 Tip/tilt & Z piezo platform with aperture



S-224 Small piezo tip/tilt mirror for high-speed beam steering tasks & image stabilization applications



S-334 Long Travel (120 mrad) 2-axis Tip-tilt platform with closed-loop control



S-330 tip-tilt platforms with closed-loop control

S-330 3-axis tip-tilt + piston platform with closed-loop control

S-323 Piezo Z/Tip/Tilt Platform

High Dynamics & Stability Nanopositioning System with Direct Metrology

The S-323 Z/tip/tilt platform integrates capacitive sensors for highest resolution and stability

- Optical Beam Deflection to 6 mrad
- Sub-µrad Resolution for High Positioning Stability
- Position Servo-Control with Capacitive Sensors
- Frictionless, High-Precision Flexure Guiding System
- System Combination with Digital Controllers for Highest Linearity

Model	Active axes	Travel range	Resolution	Unloaded resonant frequency
S-323.3CD	Z, θ_X, θ_Y	30 µm, ±1.5 mrad	0.1 nm, ±0.05 µrad	1.7 kHz

S-303 Piezo Phase Shifter

Highest Dynamics and Stability with Capacitive Feedback Sensor

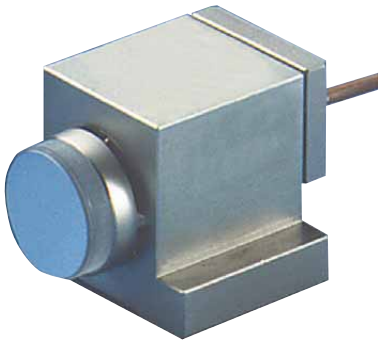
S-303 closed-loop model (left) and open-loop model (right). DIP switch for size comparison

- 25 kHz Resonant Frequency for Sub-Millisecond Dynamics
- Capacitive Sensor Option for Highest Linearity and Stability
- 3 µm Travel Range
- Compact Size: 30 mm Diameter x 10 mm
- Aperture with Open-Loop Versions
- Invar Option for Highest Thermal Stability

Model	Active axes	Closed-loop/ open-loop travel @ -20 to +120V	Closed-loop/ open-loop resolution	Unloaded resonant frequency
S-303.CD (closed-loop)/ S-302.0L (open-loop)	Z	2 / 3 µm	0.03 nm	25 kHz

S-224 – S-226 Piezo Tilt-Mirror

Fast Steering Mirror Combines Highest Dynamics and Compact Design



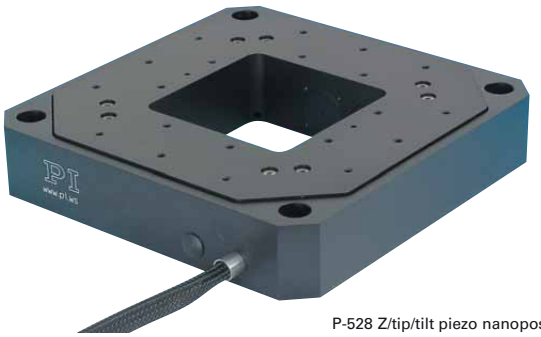
S-224 Piezo tip/tilt mirror for high-speed beam steering tasks and image stabilization applications

- Optical Beam Deflection to 4.4 mrad
- Sub-µrad Resolution, Sub-Millisecond Response
- Frictionless, High-Precision Flexure Guiding System
- Includes BK7 Mirror
- Optional Position Feedback Sensor
- Outstanding Lifetime Due to PICMA® Piezo Actuators

Model	Active axes	Open-loop tilt angle @ 0 to +100V	Closed-loop/ open-loop	Unloaded resonant

P-518, P-528, P-558 Piezo Z/Tip/Tilt Stage

High-Dynamics with Large Clear Aperture



P-528 Z/tip/tilt piezo nanopositioning system

- **1- and 3-Axis Versions**
- **Closed-Loop Vertical / Tilt Range to 200 µm / 2 mrad (Open-Loop to 240 / 2.4)**
- **Parallel Kinematics / Metrology for Enhanced Responsiveness & Multi-Axis Precision**
- **Frictionless, High-Precision Flexure Guiding System**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**
- **Clear Aperture 66 x 66 mm**
- **Capacitive Sensors for Highest Linearity**

P-5x8 series, Z/tip/tilt nanopositioners / scanners are open-frame, high-resolution, piezo-driven stages providing motion to 240 µm and 2.4 mrad with resolutions of up to 0.5 nm and 50 nrad. The 66 x 66 mm clear aperture is ideal for transmitted-light applications.

XY and XYZ multi-axis versions in the same form factor are also offered as P-517, P-527 (see p. 2-70) models with six degrees of freedom are available upon request.

Capacitive Position Sensors for Higher Accuracy

PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity . A further advantage of direct metrology with capacitive sensors is the high phase fidelity and the high bandwidth of up to 10 kHz.

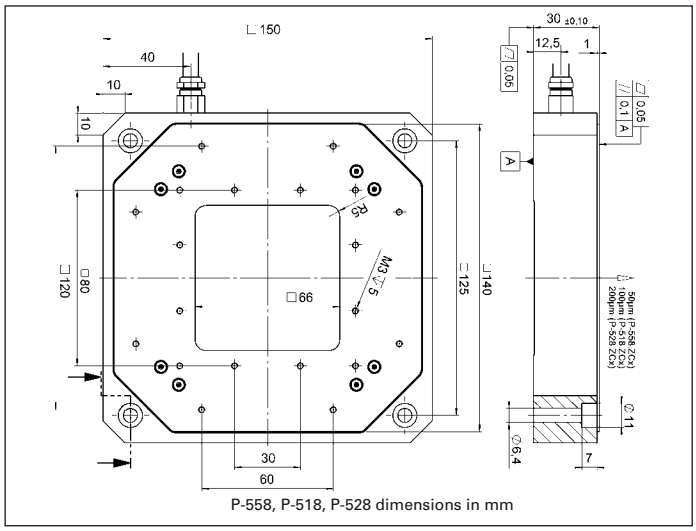
Excellent Guiding Accuracy

Flexures optimized with Finite Element Analysis (FEA) are used to guide the stage. FEA techniques are used to give the design the highest possible stiffness in, and perpendicular to, the direction of motion, and to minimize linear and angular runout. Flexures allow extremely high-precision motion, no matter how minute, as they are completely free of play and friction.

Flatness and Straightness is further enhanced by active trajectory control: Multi-axis nanopositioning systems equipped with both parallel kinematics and parallel direct metrology are able to measure platform position in all degrees of freedom against one common fixed reference. In such systems, undesirable motion from one actuator in the direction of another (cross-talk) is detected immediately and actively compensated by the servo-loops. This Active Trajectory Control Concept can keep deviation from a trajectory to under a few nanometers, even in dynamic operation.

Higher Precision in Periodic Motion

The highest dynamic accuracy in scanning applications is



P-558, P-518, P-528 dimensions in mm

Application Examples

- Metrology
- Interferometry
- Optics
- Lithography
- Scanning microscopy
- Mass storage device testing
- Laser technology
- Micromachining

Ordering Information

P-558.ZCD
Precision Nanopositioning Z-Stage, 50 µm, Direct Metrology, Capacitive Sensors, Sub-D Connector

P-558.ZCL
Precision Nanopositioning Z-Stage, 50 µm, Direct Metrology, Capacitive Sensors, LEMO Connector

P-518.ZCD
Precision Nanopositioning Z-Stage, 100 µm, Direct Metrology, Capacitive Sensors, Sub-D Connector

P-518.ZCL
Precision Nanopositioning Z-Stage, 100 µm, Direct Metrology, Capacitive Sensors, LEMO Connector

P-528.ZCD
Precision Nanopositioning Z-Stage, 200 µm, Direct Metrology, Capacitive Sensors, Sub-D Connector

P-528.ZCL
Precision Nanopositioning Z-Stage, 200 µm, Direct Metrology, Capacitive Sensors, LEMO Connector

P-558.TCD
Precision Nanopositioning Z/Tip/Tilt Stage, 50 µm, 0.6 mrad, Parallel Metrology, Capacitive Sensors, Sub-D Connector

P-518.TCD
Precision Nanopositioning Z/Tip/Tilt Stage, 100 µm, 1.4 mrad, Parallel Metrology, Capacitive Sensors, Sub-D Connector

P-528.TCD
Precision Nanopositioning Z/Tip/Tilt Stage, 200 µm, 2.4 mrad, Parallel Metrology, Capacitive Sensors, Sub-D Connector

made possible by the DDL algorithm, which is available in PI's modern digital controllers. DDL eliminates tracking errors, improving dynamic linearity and usable bandwidth by up to three orders of magnitude!

Ceramic Insulated Piezo Actuators Provide Long Lifetime

Highest possible reliability is assured by the use of award-winning PICMA® multilayer piezo actuators. PICMA® actuators are the only actuators on the market with ceramic-only insulation, which makes them resistant to ambient humidity and leakage-current failures. They are thus far superior to conventional actuators in reliability and lifetime.

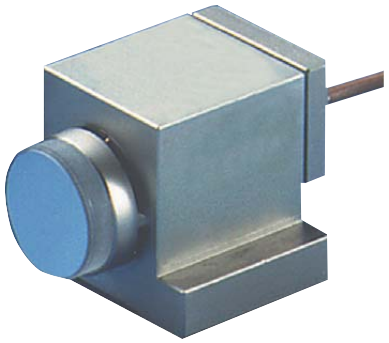
Technical Data

Model	P-558.ZCD/ P-558.ZCL	P-558.TCD	P-518.ZCD/ P-518.ZCL	P-518.TCD	P-528.ZCD/ P-528.ZCL	P-528.TCD	Units	Tolerance
Active axes	Z	Z, θ_x, θ_y	Z	Z, θ_x, θ_y	Z	Z, θ_x, θ_y		
Motion and positioning								
Integrated sensor	Capacitive	Capacitive	Capacitive	Capacitive	Capacitive	Capacitive		
Open-loop travel, -20 to +120 V	60	60	140	140	240	240	µm	min. (+20 %/-0 %)
Open-loop tip/tilt angle, -20 to +120 V	–	±0.3 mrad	–	±0.7 mrad	–	±1.2 mrad	mrad	min. (+20 %/-0 %)
Closed-loop travel	50	50	100	100	200	200	µm	
Closed-loop tip/tilt angle	–	±0.25 mrad	-	±0.5 mrad	–	±1 mrad	mrad	
Open-loop resolution	0.2	0.2	0.2	0.4	0.6	0.6	nm	typ.
Open-loop tip/tilt angle resolution	–	0.02	–	0.04	–	0.06	µrad	typ.
Closed-loop resolution	0.5	0.5	0.8	0.8	1	1	nm	typ.
Closed-loop tip/tilt resolution	–	0.05	–	0.05	–	0.1	µrad	typ.
Linearity θ_x, θ_y	–	0.03	–	0.03	–	0.03	%	typ.
Repeatability	±5	±5	±5	±5	±10	±10	nm	typ.
Repeatability θ_x, θ_y	–	±0.03	–	±0.05	–	±0.1	µrad	typ.
Runout θ_z (Z motion)	<10	<10	<10	<10	<20	<20	µrad	typ.
Runout θ_x, θ_y (Z motion)	<50	<50	<50	<50	<100	<100	µrad	typ.
Mechanical properties								
Stiffness	4	4	2.7	2.7	1.5	1.5	N/µm	±20 %
Unloaded resonant frequency (Z)	570	570	500	500	350	350	Hz	±20 %
Unloaded resonant frequency (θ_x, θ_y)	-	610	-	530	-	390	Hz	±20 %
Resonant frequency @ 30 g in Z	410	410	350	350	210	210	Hz	±20 %
Resonant frequency @ 500 g in X, Y	-	430	-	370	-	250	Hz	±20 %
Resonant frequency @2500 g in Z	245	245	200	200	130	130	Hz	±20 %
Resonant frequency @ 2500 g θ_x, θ_y	-	240	-	190	-	115	Hz	±20 %
Push/pull force capacity	100 / 50	100 / 50	100 / 50	100 / 50	100 / 50	100 / 50	N	Max.
Drive properties								
Ceramic type	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885		
Electrical capacitance	6	6	8.4	8.4	14.8	14.8	µF	±20 %
Dynamic operating current coefficient	15	15	10.5	10.5	9.2	9.2	µA/ (Hz•µm)	±20%
Miscellaneous								
Operating temperature range	-20 to 80	-20 to 80	-20 to 80	-20 to 80	-20 to 80	-20 to 80	°C	
Material	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum		
Dimensions	150 x 150 x 30	150 x 150 x 30	150 x 150 x 30	150 x 150 x 30	150 x 150 x 30	150 x 150 x 30	mm	
Mass	1380	1380	1400	1400	1420	1420	g	±5 %
Cable length	1.5	1.5	1.5	1.5	1.5	1.5	m	±10 mm
Sensor / voltage connection	CD-version: Sub-D special CL-version: LEMO	Sub-D Special	CD-version: Sub-D special CL-version: LEMO	Sub-D Special	CD-version: Sub-D special CL-version: LEMO	Sub-D Special		

Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. V alue given is noise equivalent motion with E-503 (p. 2-146) or E-710 controller (p. 2-128)
Recommended controller
CD-Versions:
Single-channel (1 per axis): E-610 servo controller / amplifier (p. 2-110), E-625 servo controller , bench-top (p. 2-114)
Single-channel digital controller: E-753 (bench-top) (p. 2-108)
CL-Versions:
Single-channel: E-500 modular piezo controller system (p. 2-142) with E-505 (p. 2-147) high-power amplifier module and E-509 servo-controller (p. 2-152)
Multi-channel versions:
Multi-channel digital controllers: E-710 bench-top (p. 2-128), E-712 modular (p. 2-140), E-725 high-power (p. 2-126), E-761 PCI board (p. 2-130)

S-224 · S-226

High-Speed Miniature Piezo Tilt Mirror



S-224 Tilt Mirror

- **Sub-µrad Resolution**
- **Sub-Millisecond Response**
- **Up to 4.4 mrad Optical Beam Deflection**
- **Closed-Loop Versions for Better Linearity**
- **Includes BK7 Mirror**
- **Zero Friction Flexure Guiding System**

S-224/S-226 miniature tilt platforms are extremely fast and compact tilt units, providing a tilt range of 2.2 mrad and submillisecond response. The S-224 and S-226 are delivered with a Ø 15 x 4 mm BK7 glass mirror.

Open- and Closed-Loop Operation

The S-224 is specifically designed for open-loop operation. The S-226 closed-loop version is available for highest accuracy and repeatability. In open-loop operation, the platform's angular position is roughly proportional to the drive voltage (see page 4-17 in the "Tutorial" section for behavior of open-loop piezos). Open-loop operation is ideal for applications where the position is controlled by data provided by an external optical sensor, a CCD camera, etc.

The closed-loop version (S-226) allows absolute position control, high linearity, and repeatability based on the internal ultra-high-resolution feedback sensor.

Working Principle / Lifetime

S-224/S-226 miniature tilt platforms are equipped with long-life, ceramic-encapsulated, high-performance PICMA® piezo drives pushing a frictionless, flexure-mounted platform. The flexure is FEA (finite element analysis) modeled for zero stiction, zero friction and exceptional guiding precision; it also serves as the pivot point and preload for the piezo actuator.

Since drives and guides are frictionless and not subject to wear and tear, these units offer an exceptionally high level of reliability.

Notes

See the "Selection Guide" on p. 3-8 for comparison with other steering mirrors.

See "Piezo Drivers & Nanopositioning Controllers" section for our comprehensive line of low-noise modular and OEM control electronics for computer and manual control.

Ordering Information

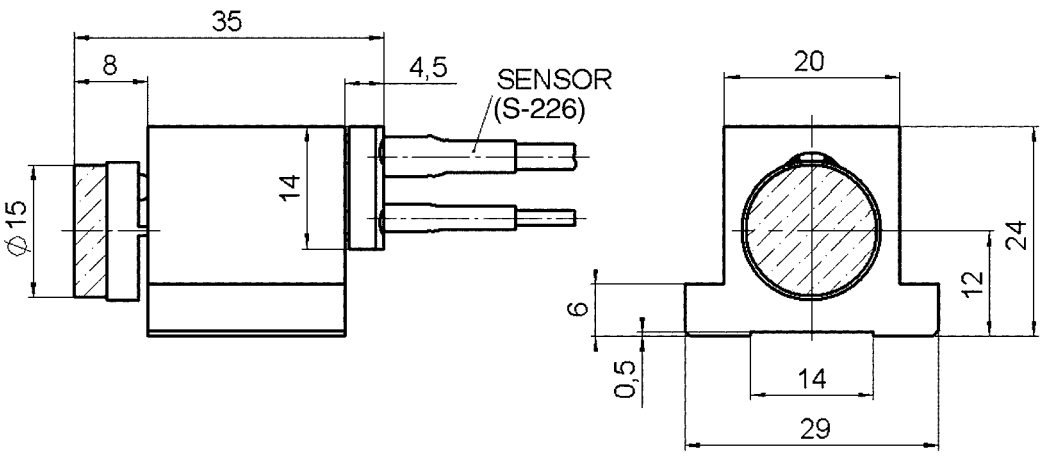
S-224.00
Piezo Tilt Platform 2.2 mrad (4.4 mrad optical) with Mirror, Open-Loop

S-226.00
Piezo Tilt Platform 2.0 mrad (4.4 mrad optical) with Mirror, Closed-Loop

Ask about custom designs!

Application Examples

- Laser beam steering & scanning
- Beam switching
- Correction of polygon scanner errors
- Laser beam stabilization



S-224, S-226 dimensions (in mm)

Technical Data

Models	S-224.00	S-226.00	Units	Notes see page 3-26
Active axes	Θ_X	Θ_X		
* Open-loop tilt angle @ 0 to 100 V	2.2	2.2	mrad ±20%	A2
* Closed-loop tilt angle	-	2.0	mrad	A3
Integrated feedback sensor	-	strain gauge		B
** Closed-loop / open-loop resolution	- / 0.05	0.1 / 0.05	µrad	C1
Closed-loop linearity (typ.)	-	0.2	%	
Full-range repeatability (typ.)	-	±3	µrad	C3
Electrical capacitance	1.5	1.5	µF ±20%	F1
*** Dynamic operating current coefficient (DOCC)	0.1	0.1	µA/(Hz x µrad)	F2
Unloaded resonant frequency (f_0)	9.0	9.0	kHz ±20%	G2
Resonant frequency w/ ø 15 x 4 mm glass mirror (included)	7.5	7.5	kHz ±20%	G3
Resonant frequency w/ ø 15 x 4 mm copper mirror	5.7	5.7	kHz ±20%	G3
Distance, pivot point to platform surface (T)	4	4	mm	
Platform moment of inertia	215	215	g · mm²	
Operating temperature range	- 20 to 80	- 20 to 80	°C	H2
Voltage connection	VL	VL		J1
Sensor connection	-	L		J2
Weight (w/o cables)	98	98	g ±5%	
Material (case / platform)	N-S / N-S	N-S / N-S		L
Recommended amplifier / controller (codes explained page 3-9)	G, C	H, D		

* Mechanical tilt, optical beam deflection is twice as large.

** For calibration information see p. 3-7. Resolution of PZT tip/tilt platforms is not limited by friction or stiction. Noise equivalent motion with E-503 amplifier.

*** Dynamic Operating Current Coefficient in µA per Hz and µrad. Example: Sinusoidal scan of 100 µrad at 10 Hz requires approximately 0.1 mA drive current.

S-334 Piezo Tip/Tilt Platform with Mirror

Fast Steering Mirror with up to 120 mrad Deflection

S-334 Tip/Tilt Mirror System / Scanner Provides Optical Deflection Angle up to 120 mrad

- **Miniature Design**
- **Optical Beam Deflection to 120 mrad (~ 6.8°)**
- **Coplanar Axes & Fixed Pivot Point; Eliminate Polarization Rotation**
- **Factory Installed Mirror**
- **Millisecond Response, Resolution to 0.2 µrad**
- **Closed-loop Position Servo-Control for High Accuracy**
- **For Mirrors up to 12.5 mm (0.5") Diameter**
- **Frictionless, High-Precision Flexure Guiding System**
- **Parallel Kinematics for Enhanced Dynamics and Better Multi-Axis Accuracy**

S-334 piezo tip/tilt mirrors / scanners provide extremely large deflection angles in a miniaturized package. These fast steering mirror systems are based on a sophisticated parallel-kinematics design with two coplanar, orthogonal axes and a fixed pivot point.

Large Tip/Tilt Ranges with Excellent Motion Characteristics

The novel flexure/lever design with minimized inertia allows for the exceptionally large tip/tilt range of 60 mrad (50 mrad in closed-loop operation, which is equivalent to 100 mrad optical beam deflection) and very fast response in the millisecond range. These parameters make the system unique in the market of piezo driven tip/tilt mirror systems.

Sub-Microradian Resolution

In addition to the large angles and the high dynamics the S-334 provides sub-microradian resolution. The integrated high-resolution, full-bridge strain gauge sensors (SGS) provide absolute position control, excellent repeatability and high linearity, typically better than 0.05 % over the entire travel range.

Differential Drive for Improved Stability and Dynamics

The S-334 is based on a parallel-kinematics design with coplanar axes and a single moving platform. Two pairs of differentially-driven piezo actuators are employed to provide the highest dynamics and position stability over a wide temperature range.

Compared to stacked, (two-stage), piezo or galvo scanners, the single-platform design provides several advantages: smaller package size, identical dynamic performance in both axes, faster response and better linearity. It also prevents polarization rotation.

High Reliability and Long Lifetime

The compact S-334 systems are equipped with preloaded PICMA® high-performance piezo actuators which are integrated into a sophisticated, FEA-modeled, flexure guiding system. The PICMA® actuators feature cofired ceramic encapsulation and provide better performance and reliability than conventional piezo actuators. Actuators, guidance and sensors are maintenance-free, not subject to wear and offer extraordinary reliability.

Ordering Information

S-334.1SD
High-Dynamics Piezo Tip/Tilt Platform, 25 mrad, SGS, Sub-D Connector, incl. Mirror

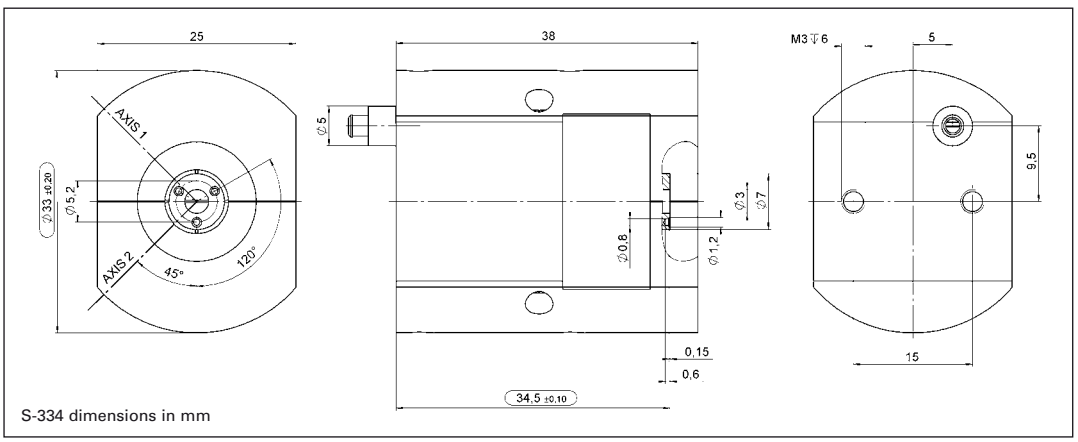
S-334.1SL
High-Dynamics Piezo Tip/Tilt Platform, 25 mrad, SGS, LEMO Connector, incl. Mirror

S-334.2SD
High-Dynamics Piezo Tip/Tilt Platform, 50 mrad, SGS, Sub-D Connector, incl. Mirror

S-334.2SL
High-Dynamics Piezo Tip/Tilt Platform, 50 mrad, SGS, LEMO Connector, incl. Mirror

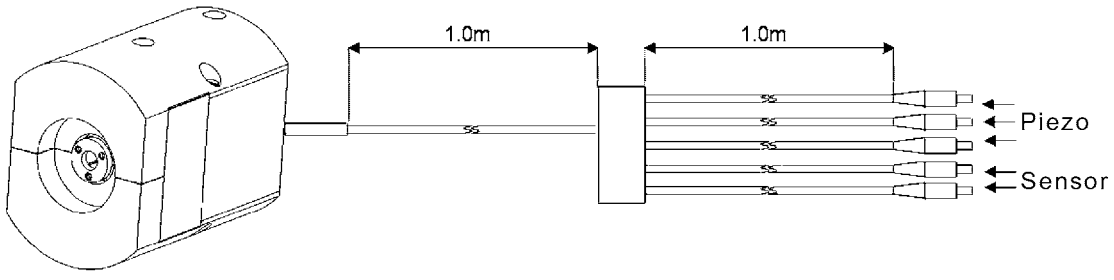
Application Examples

- Image processing / stablilization
- Interlacing, dithering
- Laser scanning / beam steering
- Optics
- Optical filters / switches
- Scanning microscopy
- Beam stabilization



S-334 dimensions in mm

Factory Installed Mirror
The S-334 is equipped with a factory-installed mirror 10 mm in diameter and 2 mm thick (flatness λ/5, reflectivity >98 % from 500 nm to 2 µm).



S-334.2SL cable configuration

Technical Data

Model	S-334.1SL S-334.1SD	S-334.2SL S-334.2SD	Units	Tolerance
Active Axes	θ_X, θ_Y	θ_X, θ_Y		
Motion and positioning				
Integrated sensor	SGS	SGS		
*Open-loop tilt angle at -20 to +120 V	30	60	mrad	min. (+20 %/-0 %)
*Closed-loop tilt angle	25	50	mrad	
Open-loop resolution	0.2	0.5	µrad	typ.
Closed-loop resolution	1	5	µrad	typ.
Linearity	0.05	0.05	%	typ.
Repeatability	2	5	µrad	typ.
Mechanical properties				
Resonant frequency underload (with standard mirrors)	3.0	1.0	kHz	±20 %
Load capacity	0.2	0.2	N	Max.
Distance of pivot point to platform surface	6	6	mm	±1 mm
Platform moment of inertia	1530	1530	g • mm²	±20 %
Standard mirror (mounted)	diameter: 10 mm, thickness: 2 mm; BK7, λ/5, R > 98 % (λ = 500 nm to 2 µm)	diameter: 10 mm, thickness: 2 mm; BK7, λ/5, R > 98 % (λ = 500 nm to 2 µm)		
Drive properties				
Ceramic type	PICMA® P-885	PICMA® P-885		
Electrical capacitance per axis	3	3	µF	±20 %
Miscellaneous				
Operating temperature range	-20 to 80	-20 to 80	°C	
Material casing	Titanium	Titanium		
Mass	0.065	0.065	kg	±5 %
Cable length	2	2	m	±10 mm
Sensor / voltage connection	LEMO connector / 25-pin sub-D connector	LEMO connector / 25-pin sub-D connector		

Recommended controller / amplifier
Closed-loop versions with D-sub connector: E-616 controller for tip/tilt mirror systems (p. 2-132);
Open-loop versions with LEMO connector: Modular piezo controller system E-500 (p. 2-142) with amplifier module E-503.00S (three channels) (p. 2-146) or 1 x E-505.00S and 2 x E-505 (high speed applications) (p. 2-147) and E-509 servo controller (p. 2-152 / 3-16)
Open-loop: E-663 three channel amplifier (p. 2-136)

Resolution of PI piezo tip/tilt platforms is not limited by friction or stiction. Noise equivalent motion with E-503 amplifier, (p. 2-146).

*Mechanical tilt, optical beam deflection is 120 mrad (open loop) and 100 mrad (closed-loop), respectively.

S-330 Piezo Tip/Tilt-Platform

High-Dynamics, Large-Angle Piezo Tip/Tilt Platforms for Fast Steering Mirrors

S-330 tip/tilt platforms with optical beam deflection angles of 4, 10 and 20 mrad

- **Resolution to 20 nrad, Excellent Position Stability**
- **Optical Beam Deflection to 20 mrad (>1°)**
- **Higher Dynamics, Stability & Linearity Through Parallel-Kinematics Design**
- **Sub-Millisecond Response**
- **For Mirrors up to 50 mm Diameter**
- **Closed-Loop Versions for Better Linearity**
- **Excellent Temperature Stability**

S-330 piezo tip/tilt platforms are fast and compact tip/tilt units, providing precise angular motion of the top platform around two orthogonal axes.

Application Examples

- Image processing / stabilization
- Interlacing, dithering
- Laser scanning / beam steering
- Optics
- Optical filters / switches
- Beam stabilization

These flexure-guided, piezoelectric platforms can provide higher accelerations than other implementations, enabling step response times in the sub-millisecond range. Closed-loop and open-loop versions with 3 different tilt ranges up to 10 mrad (20 mrad optical deflection) are available.

Parallel-kinematics design for improved stability, linearity and dynamics

PI piezo tip/tilt mirror systems are based on a parallel-kinematics design with coplanar axes and a single moving platform. Two pairs of differentially-driven piezo actuators are employed to provide the highest possible angular stability over a wide temperature range. Compared to stacked, (two-stage) piezo or galvo scanners, the single-platform design provides several advantages: smaller package size, identical dynamic performance in both axes, faster response and better linearity. It also prevents polarization rotation.

Fast Piezo Ceramic Drives

Frictionless, flexure-guided piezo ceramic drives provide higher accelerations than other actuators, such as voice-coils, and enable response in the millisecond range and below. Piezo actuators do not require energy to hold a position. The resulting low heat signature is a great advantage in infrared imaging systems like those used in astronomy.

Closed Loop Operation

For high stability and repeatability, absolute-measuring strain gauge sensors (SGS) are applied to appropriate locations on the drive train. They provide a high-bandwidth, position feedback signal to the controller. The sensors are connected in a bridge configuration to eliminate thermal drift, and assure optimal position stability. Open-loop systems are also available.

Ordering Information

S-330.2SL
High-Dynamics Piezo Tip/Tilt Platform, 2 mrad, SGS, LEMO Connector

S-330.2SD
High-Dynamics Piezo Tip/Tilt Platform, 2 mrad, SGS, Sub-D Connector

S-330.20L
High-Dynamics Piezo Tip/Tilt Platform, 2 mrad, Open-Loop, LEMO Connector

S-330.4SL
High-Dynamics Piezo Tip/Tilt Platform, 5 mrad, SGS, LEMO Connector

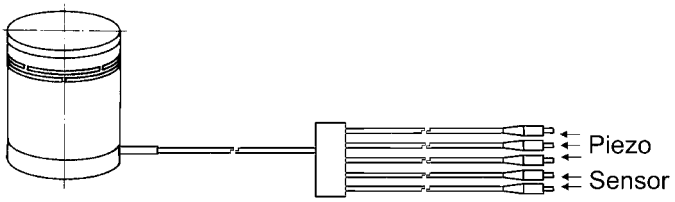
S-330.4SD
High-Dynamics Piezo Tip/Tilt Platform, 5 mrad, SGS, Sub-D Connector

S-330.40L
High-Dynamics Piezo Tip/Tilt Platform, 5 mrad, Open-Loop, LEMO Connector

S-330.8SL
High-Dynamics Piezo Tip/Tilt Platform, 10 mrad, SGS, LEMO Connector

S-330.8SD
High-Dynamics Piezo Tip/Tilt Platform, 10 mrad, SGS, Sub-D Connector

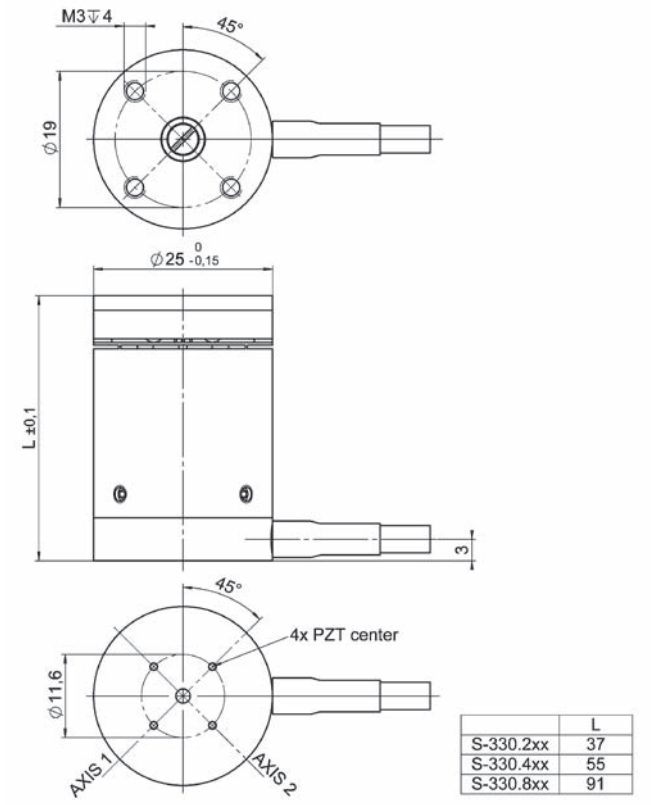
S-330.80L
High-Dynamics Piezo Tip/Tilt Platform, 10 mrad, Open-Loop, LEMO Connector



Circuit diagram and cable configuration of the S-330.xSL closed-loop versions. The S-330.xSD models feature a single Sub-D connector and can be operated by the E-616 controller.

Ceramic Insulated Piezo Actuators Provide Long Lifetime

Highest possible reliability is assured by the use of award-winning PICMA® multilayer piezo actuators. PICMA® actuators are the only actuators on the market with ceramic-only insulation, which makes them resistant to ambient humidity and leakage-current failures. They are thus far superior to conventional actuators in reliability and lifetime.



	L
S-330.2xx	37
S-330.4xx	55
S-330.8xx	91

S-330 dimensions in mm

Technical Data

Model	S-330.2SL	S-330.4SL	S-330.8SL	S-330.2SD S-330.4SD S-330.8SD	S-330.20L S-330.40L S-330.80L	Units	Tolerance
Active axes	Θ_X, Θ_Y	Θ_X, Θ_Y	Θ_X, Θ_Y	Θ_X, Θ_Y	Θ_X, Θ_Y		
Motion and positioning							
Integrated sensor	SGS	SGS	SGS	SGS	–		
Open-loop tip/tilt angle, -20 to +120 V	3.5	7	15	as SL version	as SL version	mrad	min.
Closed-loop tip/tilt angle	2	5	10	as SL version	–	mrad	
Open-loop tip/tilt angle resolution	0.02	0.1	0.2	as SL version	as SL version	µrad	typ.
Closed-loop tip/tilt resolution	0.05	0.25	0.5	as SL version	–	µrad	typ.
Linearity in Θ_X, Θ_Y	0.1	0.2	0.25	as SL version	–	%	typ.
Repeatability Θ_X, Θ_Y	0.15	0.5	1	as SL version	–	µrad	typ.
Mechanical properties							
Unloaded resonant frequency (Θ_X, Θ_Y)	3.7	3.3	3.1	as SL version	as SL version	kHz	±20%
Resonant frequency loaded in Θ_X, Θ_Y (with 25 x 8 mm glass mirror)	2.6	1.6	1.0	as SL version	as SL version	kHz	±20%
Distance of pivot point to platform surface	6	6	6	6	6	mm	±1 mm
Platform moment of inertia	1530	1530	1530	1530	1530	g x mm²	±20%
Drive properties							
Ceramic type	PICMA®	PICMA®	PICMA®	PICMA®	PICMA®		
Electrical capacitance	3/axis	6/axis	12.5/axis	as SL	as SL	µF	±20%
Dynamic operating current coefficient	0.22/axis	0.4/axis	0.8/axis	as SL	as SL	µA//Hz • mrad)	±20%
Miscellaneous							
Operating temperature range	-20 to 80	-20 to 80	-20 to 80	-20 to 80	-20 to 80	°C	
Material case	Stainless steel	Stainless steel	Stainless steel	Stainless steel	Stainless steel		
Material platform	Invar	Invar	Invar	Invar	Invar		
Mass	0.2	0.38	0.7	as SL version	as SL version	kg	±5%
Cable length	1.5	1.5	1.5	1.5	1.5	m	±10 mm
Sensor / voltage connection	LEMO	LEMO	LEMO	Sub-D connector	LEMO		

Recommended controller / amplifier

Versions with LEMO connector: modular piezo controller system E-500 (p. 2-142) with amplifier module E-503.00S (three channels) (p. 2-146) or 1 x E-505.00S and 2 x E-505 (high speed applications) (p. 2-147) and E-509 controller (p. 2-152) (optional)

Open-loop: E-663 three channel amplifier (p. 2-136)

Versions with Sub-D connectors: E-616 servo controller for tip/tilt mirror systems (p. 2-132)

S-325 Piezo Z/Tip/Tilt Platform

High-Speed Tripod System for Mirrors and Optics

S-325.30L piezoelectric fast steering mirror platform / scanner

- **Optical Beam Deflection to 10 mrad, Resolution to 50 nrad**
- **Piston Movement up to 30 µm (for Path Length Adjustment)**
- **Compact Tripod Design with Coplanar Axes Eliminates Polarization Rotation**
- **Sub-Millisecond Responsiveness**
- **Closed-Loop Versions for Higher Precision**
- **For Mirrors up to 25 mm (1") Diameter**
- **Frictionless, High-Precision Flexure Guiding System**
- **Parallel Kinematics for Enhanced Dynamics and Better Multi-Axis Accuracy**

The S-325 Z/tip/tilt platforms and actuators provide high speed and precise movement of the platform in two tilt axes as well as sub-nanometer linear resolution with sub-millisecond response. The design is based on a parallel-kinematics direct-drive piezo tripod (see p. 2-83), and they are especially optimized for industrial applications where 1.000.000.000 motion cycles have to be performed without failure or performance degradation. The systems are designed for mirrors and optics up to 25 mm in diameter and can be mounted in any orientation.

The tripod drive offers optimum angular stability over a wide temperature range. Compared to stacked, (two-stage), piezo or galvo scanners, the single platform design provides several advantages: smaller package size, identical size, identical dynamic performance in all axes, faster response and better linearity. It also prevents polarization rotation.

All three piezo linear actuators can be driven individually (for tip/tilt movement) or in parallel (for vertical movement) by a three-channel amplifier.

High Resolution, Stability and Dynamics

The S-325 offers piston movement of up to 30 µm (ideal for path length adjustment) and mechanical tilt up to 5 mrad (equivalent to 10 mrad optical beam deflection). The zero-friction piezo drives and flexure guidance allow sub-nanometer linear resolution and sub-microradian angular resolution.

Ordering Information

S-325.3SD
High-Dynamics Piezo Z/Tip/Tilt Platform, 5 mrad, 30 µm, SGS, Sub-D Connector

S-325.3SL
High-Dynamics Piezo Z/Tip/Tilt Platform, 5 mrad, 30 µm, SGS, LEMO Connector

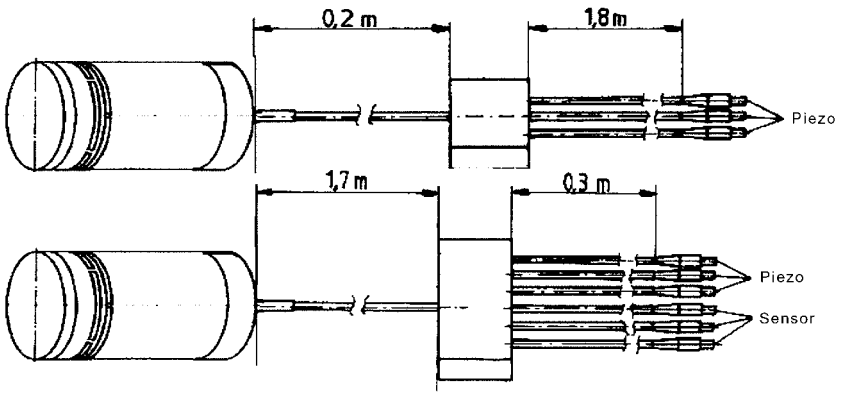
S-325.30L
High-Dynamics Piezo Z/Tip/Tilt Platform, 5 mrad, 30 µm, Open-Loop, LEMO Connector

Open-Loop and Closed-Loop Operation

In open-loop mode, the platform linear motion is roughly proportional to the applied voltage. The S-325.30L open-loop model is ideal for high-bandwidth, high-resolution applications where the absolute angular position is of secondary importance (e. g. for tracking) or where feedback is provided by an external sensor (e. g. CCD, PSD). The S-325.3SL model is equipped with high-resolution strain gauge sensors and provides absolute position control, high linearity and high repeatability. The new E-616 controller/driver module (see p. 2-132) is ideally suited for tip/tilt OEM applications.

Application Examples

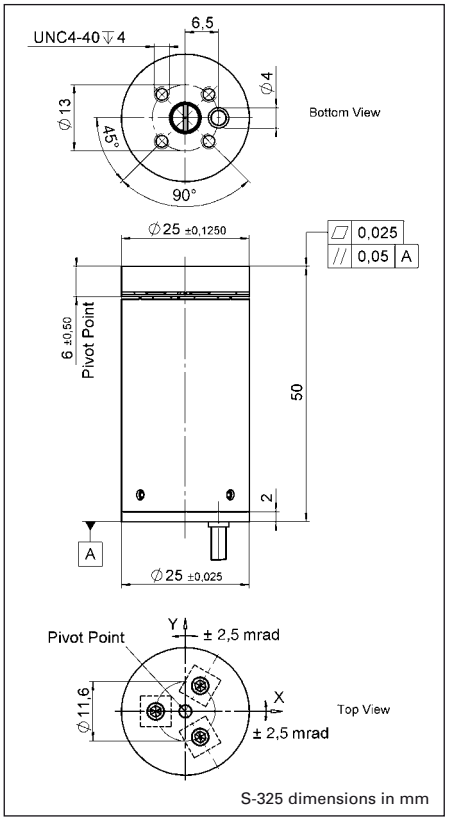
- Image processing / stablilization
- Optical trapping
- Laser scanning / beam steering
- Laser tuning
- Optical filters / switches
- Optics
- Beam stabilization



S-325 cable configuration (top: S-325.30L, bottom: S-325.3SL)

High Reliability and Long Lifetime

The compact S-325 systems are equipped with preloaded PICMA® high-performance piezo actuators which are integrated into a sophisticated, FEA-modeled, flexure guiding system. The PICMA® actuators feature cofired ceramic encapsulation and provide better performance and reliability than conventional piezo actuators. Actuators, guidance and sensors are maintenance-free, not subject to wear and offer extraordinary reliability.



S-325 dimensions in mm

Technical Data

Model	S-325.30L	S-325.3SL	S-325.3SD	Units	Tolerance
Active axes	Z, Θ_X, Θ_Y	Z, Θ_X, Θ_Y	Z, Θ_X, Θ_Y		
Motion and positioning					
Integrated sensor	–	SGS	SGS		
Open-loop travel, 0 to +100 V	30	30	30	µm	min. (+20 %/-0 %)
Open-loop tip/tilt angle, 0 to +100 V	5	5	5	mrad	min. (+20 %/-0 %)
Closed-loop travel	–	30	30	µm	
Closed-loop tip/tilt angle	–	4	4	mrad	
Open-loop resolution	0.5	0.5	0.5	nm	typ.
Open-loop tip/tilt angle resolution	0.05	0.05	0.05	µrad	typ.
Closed-loop linear resolution	–	0,6	0,6	nm	typ.
Closed-loop tip/tilt resolution	–	0.1	0.1	µrad	typ.
Mechanical properties					
Unloaded resonant frequency	2	2	2	kHz	±20 %
Resonant frequency (with 25 x 8 mm glass mirror)	1	1	1	kHz	±20 %
Distance of pivot point to platform surface	6	6	6	mm	±0.5 mm
Platform moment of inertia	515	515	515	g • mm²	±20 %
Drive properties					
Ceramic type	PICMA® P-885	PICMA® P-885	PICMA® P-885		
Electrical capacitance	9.3	9.3	9.3	µF	±20 %
Dynamic operating current coefficient	39	39	39	µA / (Hz • mrad)	±20 %
Miscellaneous					
Operating temperature range	-20 to 80	-20 to 80	-20 to 80	°C	
Material casing	Aluminum	Aluminum	Aluminum		
Mass	0.065	0.065	0.065	kg	±5 %
Cable length	2	2	1.5	m	±10 mm
Sensor / voltage connection	LEMO	LEMO	Sub-D		

For maximum tilt range, all three piezo actuators must be biased at 50 V. Due to the parallel-kinematics design linear travel and tilt angle are interdependent. The values quoted here refer to pure linear / pure angular motion. See equations (p. 2-84).

Recommended controller / amplifier

Versions with LEMO connector: modular piezo controller system E-500 (p. 2-142) with amplifier module E-503.00S (three channels) (p. 2-146) or 1 x E-505.00S and 2 x E-505 (high speed applications) (p. 2-147) and E-509 controller (p. 2-152) (optional)

Single-channel (1 per axis): E-610 OEM servo controller / amplifier (p. 2-110), E-625 servo controller bench-top (p. 2-114)

Versions with Sub-D connectors: E-616 servo controller for tip/tilt mirror systems (p. 2-132)

S-340 Piezo Tip / Tilt-Platform

High-Dynamics for Mirrors and Optics with a Diameter of up to 100 mm (4")

S-340 tip / tilt platform for mirrors with a diameter of up to 100 mm

- **Resolution up to 20 nrad, Excellent Position Stability**
- **Optical Beam Deflection to 4 mrad**
- **Higher Precision and Dynamics via Parallel Kinematics**
- **Only One Moving Platform with a Fixed Pivot Point Prevents the Change of the Polarization**
- **Sub-ms Response**
- **For Mirrors with a Diameter up to 100 mm**
- **Position-Controlled Versions for Better Linearity**
- **Excellent Temperature Stability**

Ordering Information

S-340.A0L
Piezo Tip / Tilt Platform, 2 mrad, Open-Loop, LEMO Connector, Aluminum Top Plate

S-340.ASL
Piezo Tip / Tilt Platform, 2 mrad, SGS, LEMO, Aluminum Top Plate

S-340.ASD
Piezo Tip / Tilt Platform, 2 mrad, SGS, Sub-D Connectors, Aluminum Top Plate

Various material for the top platforms are available on demand:

S-340.S0L / .SSL / .SSD: High-Grade Steel

S-340.T0L / .TSL / .TSD: Titanium

S-340.i0L / .iSL / .iSD: Invar

S-340 tip / tilt platforms allow high-dynamic and precise angular movements of the top platform in two orthogonal axes with a common pivot point (parallel kinematics).
The systems are designed for mirrors with a diameter of up to 100 mm and their differential drive enables an outstanding angular stability in a wide temperature range. A variety of top platforms are available to achieve an optimum thermal adaptation to different mirror materials. For operation in closed-loop, the SD versions are equipped with high-resolution strain gauge sensors in a thermally stable circuit. All versions feature a sub-µrad resolution and a tip / tilt range of 2 mrad (equivalent to 4 mrad optical beam deflection).

Application Examples

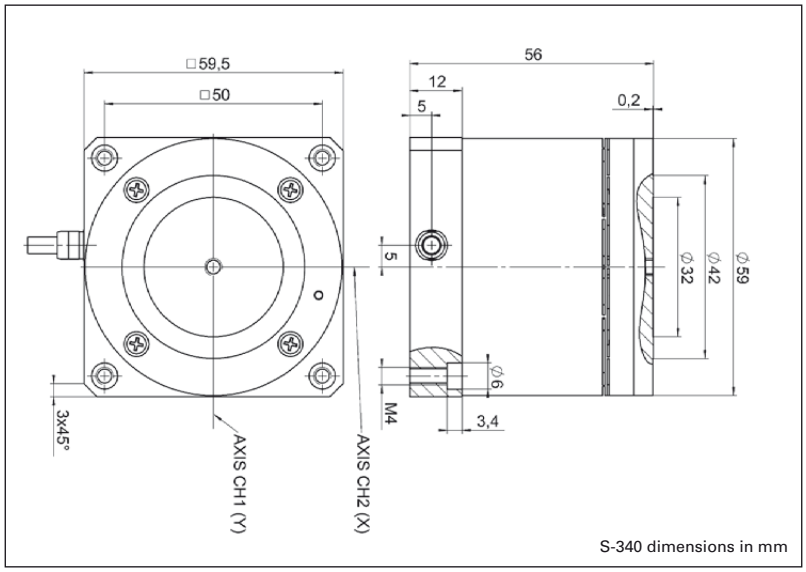
- Image processing / stablilization
- Laser scanning / beam steering
- Active and adaptive optics
- Optical filters
- Beam stabilization
- Correction of polygon mirror errors

Parallel-Kinematic Design for Improved Stability, Linearity and Dynamics

Piezo tip / tilt mirror systems of PI are based on parallel kinematics with a single movable platform for all directions of motion. The four actuators are controlled differentially in pairs depending on the tip / tilt movement of the platform. This results in an excellent stability in linear and angular positioning for a wide temperature range. Compared to systems with an independent positioner per tilt axis, parallel-kinematics offer the advantage of symmetrical dynamic properties of motion for all axes, faster response and better linearity with a compact design. For this kind of design no change of polarization of the reflected light occurs, different than for stacked single axis systems like e. g. galvo scanners.

Ceramic-Insulated Piezo Actuators Provide Superior Lifetime

The highest possible reliability is assured by employing the award-winning PICMA® multilayer piezo actuators. PICMA® actuators are the only actuators on the market with a ceramic-only insulation which makes them resistant to ambient humidity and leakage-current failures. They are thus far superior to conventional actuators in reliability and lifetime.



S-340 dimensions in mm

Technical Data

Model	S-340.ASD/.ASL	S-340.A0L	Units	Tolerance
Active axes	θ X, θY	θX, θY		
Motion and Positioning				
Integrated sensor	SGS	–		
Open-loop tip / tilt angle, -20 to +120 V	2	2	mrad	min.
Closed-loop tip / tilt angle	2	–	mrad	
Open-loop tip / tilt angle resolution	0.02	0.02	µrad	typ.
Closed-loop tip / tilt resolution	0.2	–	µrad	typ.
Linearity in θX, θY	0.1	–	%	typ.
Repeatability in θX, θY	0.15	–	µrad	typ.
Mechanical properties				
Unloaded resonant frequency (θX, θY)	1.4	1.4	kHz	±20 %
Resonant frequency loaded in θX, θY (with glass mirror diameter 50 mm, thickness 15 mm)	0.9	0.9	kHz	±20 %
Resonant frequency loaded in θX, θY (with glass mirror diameter 75 mm, thickness 22 mm)	0.4	0.4	kHz	±20 %
Distance of pivot point to platform surface	7.5	7.5	mm	±1 mm
Platform moment of inertia	18000	18000	g · mm²	±20 %
Drive properties				
Ceramic type	PICMA®	PICMA®		
Electrical capacitance	6 / axis	6 / axis	µF	±20 %
Dynamic operating current coefficient	0.45 / axis	0.45 / axis	µA / (Hz · mrad)	±20 %
Miscellaneous				
Operating temperature range	-20 to 80	-20 to 80	°C	
Material case	Aluminum	Aluminum		
Material platform	Aluminum; or optionally Steel, Titanium or Invar	Aluminum; or optionally Steel, Titanium or Invar		
Mass	0.355	0.35	kg	±5 %
Cable length	2	2	m	±10 mm
Sensor / voltage connection	Sub-D connector / LEMO	LEMO		

Recommended controller / amplifier
Closed-loop versions with Sub-D connectors: E-616 servo controller for tip / tilt mirror systems s. p. 2-132; with LEMO connector: E-500 System s. p. 2-142.
Open-loop: E-500 System s. p. 2-142.

S-310 – S-316 Piezo Z/Tip/Tilt Scanner

High-Speed System with Clear Aperture

S-310.10, S-316.10
piezo systems for scanning,
optics alignment and mirror shifter alignment

- **10 mm Clear Aperture**
- **Piezo Tripod Design**
- **Optical Beam Deflection to 2,4 mrad**
- **Piston Movement up to 12 µm (phase shifter)**
- **Sub-Millisecond Response, Sub-Microradian Resolution**
- **Closed-Loop Versions for Higher Precision**
- **For Optics, Mirrors or Other Components**
- **Frictionless, High-Precision Flexure Guiding System**
- **Parallel Kinematics for Enhanced Dynamics and Better Multi-Axis Accuracy**

S-310 to S-316 multi-axis tip/tilt platforms and Z-positioners are fast, compact units based on a piezo tripod design. They offer piston movement up to 12 µm and tilt movement up to 1.2 mrad (2.4 mrad optical beam deflection) with sub-millisecond response and settling. The tripod design features optimum angular stability over a wide temperature range.

The systems are designed for mirrors and optics up to 25 mm in diameter and can be mounted in any orientation; the clear aperture is ideal for transmitted-light applications (e.g. for optical filters).

Application Examples

- Image processing / stablilization
- Interferometry
- Laser scanning / beam steering
- Laser tuning
- Optical filters / switches
- Beam stabilization

Open-Loop and Closed-Loop Operation

In open-loop mode, the tip/tilt angle is roughly proportional to the applied voltage. The S-310 to S-315 open-loop models are ideal for high-speed, high resolution applications where the absolute angular position is of secondary importance (e.g. for tracking) or where feedback is provided by an external sensor (e.g. CCD, PSD). The S-316.10 model is equipped with high-resolution strain gauge sensors and provides absolute position control, high linearity and high repeatability.

Available Versions

S-310.10, S-314.10

Open-loop Z-platforms; all three piezo linear actuators are electrically connected in parallel, providing vertical positioning (piston movement) of the top ring. Only one drive channel is required.

S-311.10, S-315.10

Open-loop Z/tip/tilt positioners; all three piezo linear actuators can be driven individually (or in parallel) by a three-channel amplifier. Vertical (piston movement) positioning and tip/tilt positioning are possible.

S-316.10

Closed-loop Z/tip/tilt positioner. All three piezo linear actuators are equipped with strain gauge position feedback sensors and can be driven individually (or in parallel) by a three-channel amplifier with a position servo-controller. Vertical positioning (piston movement) and tip/tilt positioning are possible. The integrated position feedback sensors provide sub-microradian resolution and high repeatability.

Ordering Information

S-310.10
Piezo Actuator, Clear Aperture, 6 µm, LEMO Connector

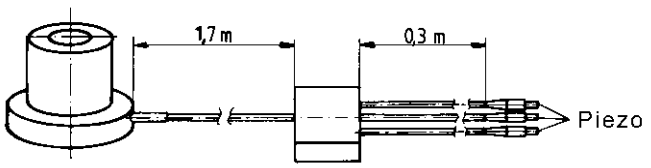
S-311.10
Piezo Z/Tip/Tilt Platform, Clear Aperture, 600 µrad, 6 µm, LEMO Connector

S-314.10
Piezo Actuator, Clear Aperture, 12 µm, LEMO Connector

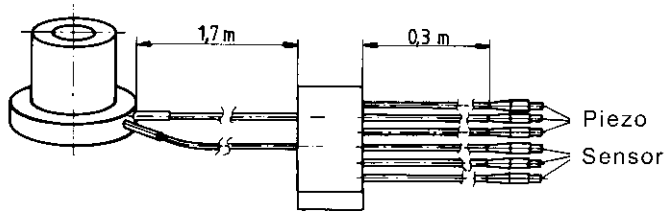
S-315.10
Piezo Z/Tip/Tilt Platform, Clear Aperture, 1.2 mrad, 12 µm, LEMO Connector

S-316.10
Piezo Z/Tip/Tilt Platform, Clear Aperture, 1.2 mrad, 12 µm, SGS, LEMO Connector

S-316.10D
Piezo Z/Tip/Tilt Platform, Clear Aperture, 1.2 mrad, 12 µm, SGS, Sub-D Connector



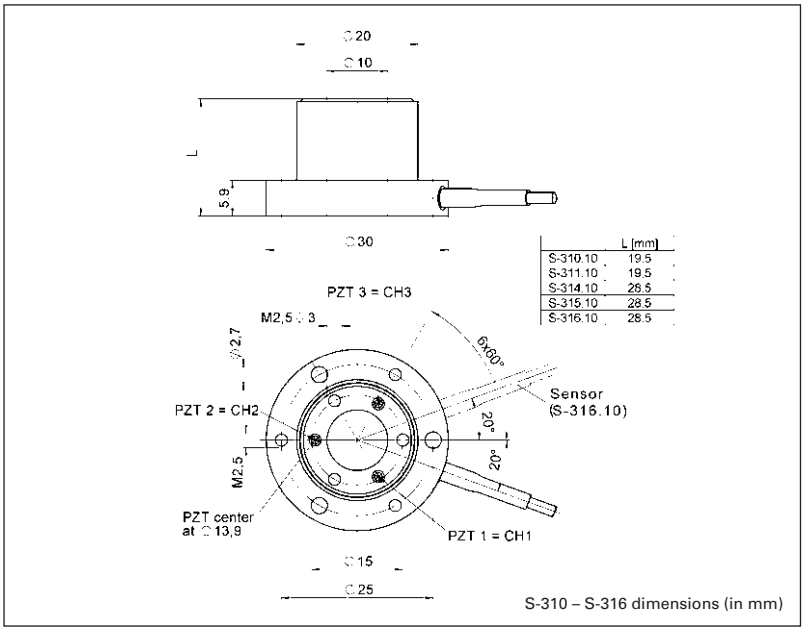
S-315 cable configuration



S-316 cable configuration

High Reliability and Long Lifetime

The compact S-310 - S-316 systems are equipped with preloaded PICMA® high-performance piezo actuators which are integrated into a sophisticated, FEA-modeled, flexure guiding system. The PICMA® actuators feature cofired ceramic encapsulation and provide better performance and reliability than conventional piezo actuators. Actuators, guidance and sensors are maintenance-free, not subject to wear and offer extraordinary reliability.



S-310 – S-316 dimensions (in mm)

Technical Data

Model	S-310.10	S-314.10	S-311.10	S-315.10	S-316.10	Units	Tolerance
Active axes	Z	Z	Z, Θ_X, Θ_Y	Z, Θ_X, Θ_Y	Z, Θ_X, Θ_Y		
Motion and positioning							
Integrated sensor	–	–	–	–	SGS		
Open-loop travel, 0 to +100 V	6 / –	12 / –	6 / –	12 / –	12 / 12	µm	min. (+20 %/-0 %)
*Open-loop tilt angle @ 0 to 100 V	–	–	600	1200	1200	µrad	min. (+20 %/-0 %)
Closed-loop travel	–	–	–	–	12	µm	
*Closed-loop tilt angle	–	–	–	–	1200	µrad	
Open-loop resolution	0.1	0.2	0.1	0.2	0.2	nm	typ.
Open-loop tip/tilt angle resolution			0.02	0.05	0.05	µrad	typ.
Closed-loop resolution	–	–	–	–	0.4	nm	typ.
Closed-loop tip/tilt resolution	–	–	–	–	0.1	µrad	typ.
Linearity	–	–	–	–	0.2	%	typ.
Mechanical properties							
Stiffness	20	10	20	10	10	N/µm	±20 %
Unloaded resonant frequency (Z)	9.5	5.5	9.5	5.5	5.5	kHz	±20 %
Resonant frequency (with 15 x 4 mm glass mirror)	6.5	4.4	6.5	4.1	4.1	kHz	±20 %
Resonant frequency (with 20 x 4 mm glass mirror)	6.1	4.2	6.1	3.4	3.4	kHz	±20 %
Distance of pivot point to platform surface	–	–	5	5	5	mm	±1 mm
Platform moment of inertia	–	–	150	150	150	g • mm²	±20 %
Drive properties							
Ceramic type	PICMA® P-882	PICMA® P-882	PICMA® P-882	PICMA® P-882	PICMA® P-882		
Electrical capacitance	0.39	0.93	0.39	0.93	0.93	µF	±20 %
Dynamic operating current coefficient	8	10	8	10	10	µA / (Hz • mrad)	±20 %
Miscellaneous							
Operating temperature range	-20 to 80	-20 to 80	-20 to 80	-20 to 80	-20 to 80	°C	
Material	Stainless steel	Stainless steel	Stainless steel	Stainless steel	Stainless steel		
Mass	0.045	0.055	0.045	0.055	0.055	kg	±5%
Cable length	2	2	2	2	2	m	±10 mm
Sensor connection	–	–	–	–	LEMO		
Voltage connection	LEMO	LEMO	LEMO	LEMO	LEMO		

Resolution of PI piezo tip/tilt platforms is not limited by friction or stiction. Noise equivalent motion with E-503 amplifier (p. 2-146).

*Mechanical tilt, optical beam deflection is twice as large. For maximum tilt range, all three piezo actuators must be biased at 50 V. Due to the parallel-kinematics design linear travel and tilt angle are interdependent. The values quoted here refer to pure linear / pure angular motion (equations p. 2-84).

Recommended controller / amplifier
Single-channel (1 per axis): E-610 servo-controller / amplifier (p. 2-110), E-625 servo-controller, bench-top (p. 2-114)

Multi-channel: modular piezo controller system E-500 (p. 2-142) with amplifier module E-503 (three channels) (p. 2-146) or E-505 (1 per axis, high-power) (p. 2-147) and E-509 controller (p. 2-152) (optional), E-517 interface module (p. 2-156) (optional)

S-303

High-Speed Piezo Phase Shifters with Direct Metrology Option

S-303 closed-loop model (left) and open-loop model (right). Dip switch for size comparison.

- **25 kHz Resonant Frequency for Sub-Millisecond Dynamics**
- **<0.1 Nanometer Resolution**
- **Capacitive Sensor Option for Highest Linearity and Stability**
- **Invar Option for Highest Thermal Stability**
- **Aperture with Open-Loop Versions**
- **3 µm Travel Range**
- **Compact Size: 30 mm Diameter x 10 mm**

S-303 phase shifters are extremely fast and compact systems based on a piezo tripod drive. They offer angstrom level resolution, piston movement up to 3 µm with sub-msec response and settling dynamics. The S-303 is designed for mirrors and optics up to 25 mm diameter and can be mounted in any orientation. Open- and closed-loop versions are available.

S-303.0L: Open-Loop Z-Positioner

The S-303.0L open-loop model is ideal for applications where the position is controlled by an external loop and an external sensor. The platform position corresponds roughly to the drive voltage of the piezo actuators. The clear aperture was integrated for transmitted-light applications.

S-303.CD: Superior Accuracy Through Direct-Motion-Metrology Capacitive Feedback Sensors

The S-303.CD closed-loop models are equipped with non-contact, zero-friction, direct-measuring two-plate capacitive position sensors and were designed for applications requiring nanometer positioning accuracy and stability. Capacitive sensors are absolute-measuring high-bandwidth devices and exhibit no periodic errors. Unlike conventional sensors, direct metrology measures the position of the platform directly rather than the strain in the actuator or guiding system. It improves phase fidelity and permits motion linearity of better than 0.03 % and effective resolution of better than 0.1 nanometers. This technique, combined with the inherent precision of the PI two-plate capacitive sensor and the temperature-compensated design, results in higher linearity scans, and provides superior responsiveness, resolution, repeatability and stability.

Working Principle / Lifetime

S-303 systems were developed for industrial applications where 10^9 motion cycles or more must be performed without failure or performance loss. The S-303 drive units incorporate PICMA® low-voltage multilayer piezo actuators. These highly optimized and ceramic-encapsulated drives are more robust than conventional piezo actuators, and feature superior lifetime in static and dynamic applications. Since drives and sensors in the S-303 are frictionless and not subject to wear and tear, these units offer an exceptionally high level of reliability.

Application Examples

- Interferometry
- Optical path tuning
- Beam stabilization
- Laser physics
- Cavity tuning

Ordering Information

S-303.0L
Piezo Phase Shifter, 3 µm, Open-Loop

S-303.CD
Piezo Phase Shifter, 2 µm, Capacitive Sensor

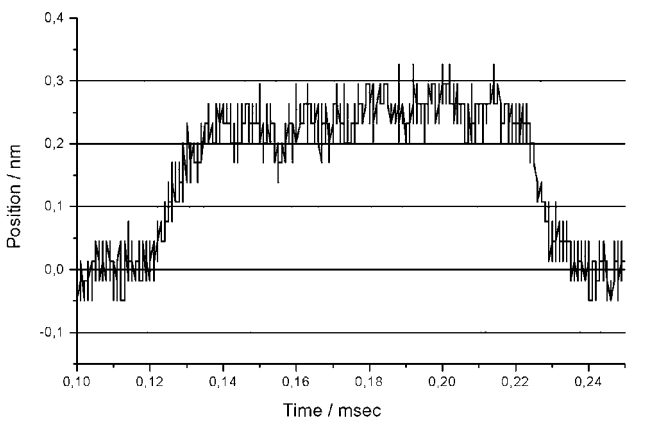
S-303.0Li
Piezo Phase Shifter, 3 µm, Open-Loop, Invar

S-303.CDi
Piezo Phase Shifter, 2 µm, Capacitive Sensor, Invar

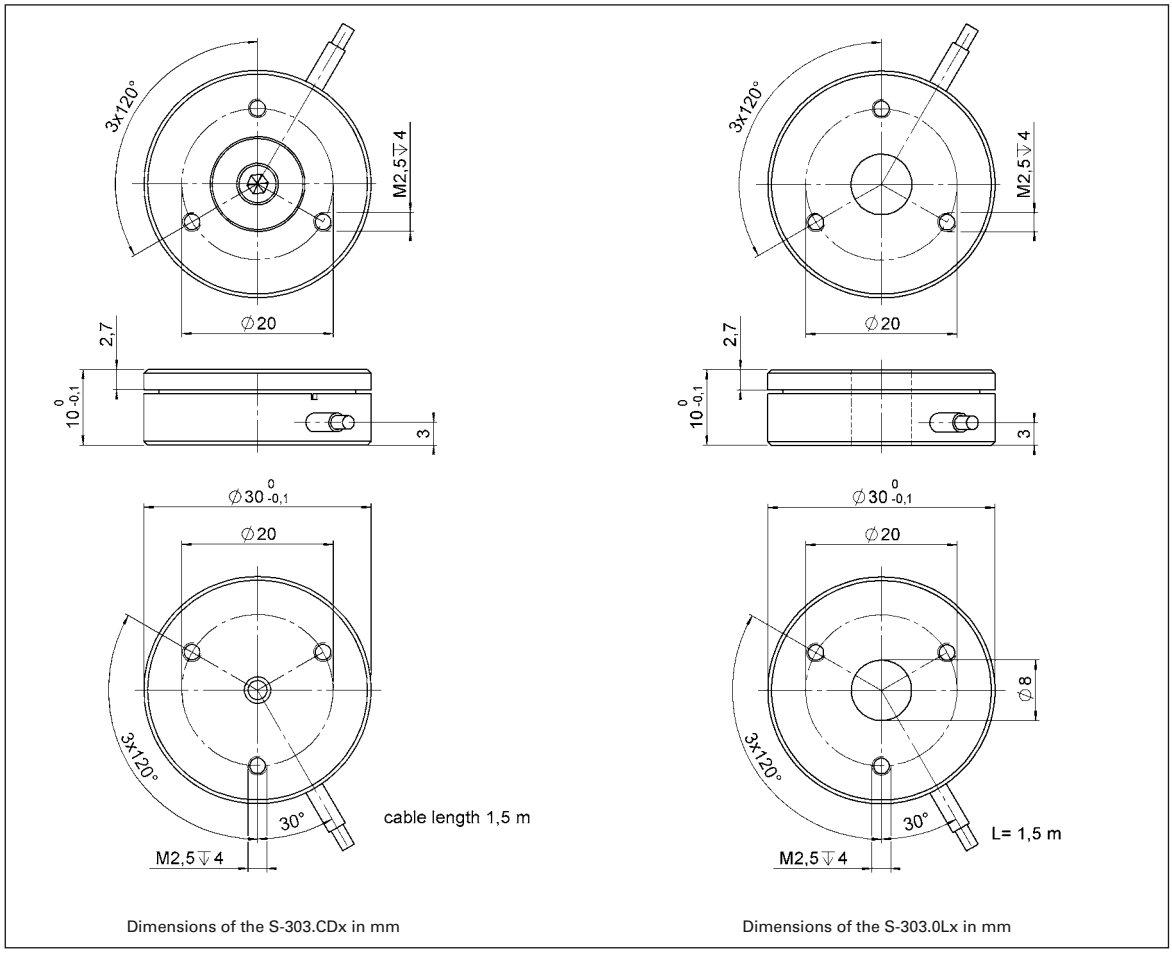
Ask about custom designs!

Notes

See the "Selection Guide" on p. 3-8 for comparison with other steering mirrors.



A 250 picometer step (0.25 nm) of the S-303 platform, controlled by an E-503 amplifier module and an E-509.C1A servocontroller module. Measured with special ultra-high-resolution capacitive gauge, ±0.02 nm resolution.



Dimensions of the S-303.CDx in mm

Dimensions of the S-303.0Lx in mm

Technical Data

Models	S-303.CDx	S-303.0Lx	Units	Notes see page 3-26
Active axes	Z	Z		
Min. Open-loop travel @ -20 to +120 V	3	3	µm ±20%	A2
Closed-loop travel	2	-	µm	A5
Integrated feedback sensor	capacitive	-		B
* Closed-loop / open-loop resolution	0.03 / 0.03	- / 0.03	nm	C1
** Closed-loop linearity (typ.)	1.0	-	%	
Full-range repeatability (typ.)	0.7	-	nm	C
Stiffness			N/µm ±20%	D1
Max. (±) normal load	0.5	0.5	N	D4
Electrical capacitance	0.9	0.9	µF ±20%	F1
*** Dynamic operating current coefficient (DOCC)	50	50	µA/(Hz x µm)	F2
Unloaded resonant frequency	25	25	kHz ±20%	G2
Operating temperature range	-20 to 80	-20 to 80	°C	H2
Voltage connection	D	VL		J1
Sensor connection	D	-		J2
Mass	100	30	g ±5%	
Body material	Al, Invar optional	Al, Invar optional		L
Recommended Amplifier / Controller (codes explained page 3-9)	F, M	G, C		

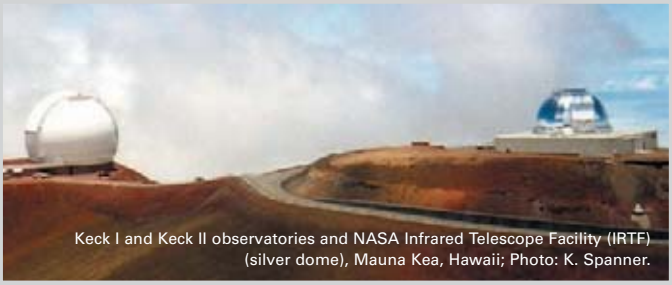
* For calibration information see p. 3-7. Resolution of PZT Nanopositioners is not limited by friction or stiction. Noise equivalent motion with E-503, E-710.

** With digital controller, analog controllers will provide a linearity of typ. 1 nm.

*** Dynamic Operating Current Coefficient in µA per Hz and µm. Example: Sinusoidal scan of 1 µm at 10 Hz requires approximately 0.5 mA drive current.

Custom Systems for Telescopes

PI Steering Mirrors and Alignment Systems in Astronomy



Keck I and Keck II observatories and NASA Infrared Telescope Facility (IRTF) (silver dome), Mauna Kea, Hawaii; Photo: K. Spanner.

The Horsehead Nebula; Photo: Brian Lula.

Resolution in large earthbound telescopes is limited by atmospheric turbulence and vibrations. During the last 15 years PI has designed several large-aperture tip/tilt systems for image stabilization. Piezoelectrically driven active secondary mirrors can improve the effective resolution up to 1000 % by correcting for these image shifts in real time, especially during long integrations with weak light sources.

Momentum Compensation
Due to the inertia of the large mirrors and the high accelerations required to correct for image fluctuations, significant forces can be induced in the telescope structure, causing unwanted vibrations. PI has developed momentum compensation systems integrated into the tip/tilt platforms which cancel undesirable vibrations and thus offer significantly better stabilization than uncompensated systems.

Active tip/tilt mirror system for the Keck Outrigger telescope in Hawaii. The units are controlled by a high-performance digital controller with a fiber optic interface (not shown).
Mirror diameter: 250 mm
Tip/tilt range: ±150 µrad
Resolution: nanoradian range
Position measurement: capacitive

25cm secondary mirror

Piezo driven steering platform, µm/mrad range; nm/nrad precision

Momentum compensation

Hexapod actuators range: mm/degrees resolution: µm/µrad

Base plate

Example of a combined high-speed piezo tip/tilt plaftform with a long range, low-speed 6-axis hexapod alignment system

High-Resolution Linear Actuators
273 PI actuators are used for tip/tilt/piston movement of segmented mirror panels in the SALT Telescope.
Features: 16 nm design resolution; 0.15 µm minimum incremental motion; non-rotating tip, compact design.

Program Overview

- Piezo Ceramic Actuators & Motors
- Piezo Nanopositioning Systems and Scanners
- Active Optics / Tip-Tilt Platforms
- Capacitive Nanometrology Sensors
- Piezo Electronics: Amplifiers and Controllers
- Hexapod 6-Axis Positioners / Robots
- Micropositioning Stages & Actuators
- Photonics Alignment Systems, Solutions for Telecommunications
- Motor Controllers
- Ultrasonic Linear Motors

Request or download the complete PI Nanopositioning & Piezo Actuator Catalog

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